L Number	Hits	Search Text	DB	Time stamp
-	10	semiconductor and load near3 port near3 table	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 09:56
-	4079	fuop	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 09:56
-	24	semiconductor and fuop	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 09:58
-	229	semiconductor and foup	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 10:08
-	5993	load near3 port	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 10:09
-	70	(semiconductor and foup) and (load near3 port)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 10:10
-	2862706	(metrology or measuring or measure$4 or detect$3).ab,ti.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 16:54
-	15	((semiconductor and foup) and (load near3 port)) and ((metrology or measuring or measure$4 or detect$3).ab,ti.)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 10:54
-	0	((semiconductor and foup) and (load near3 port)) and 76013920.uref,bi.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 10:54
-	12	6013920.uref,bi.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 16:16
-	1618	cluster near2 tool	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 16:17
-	1354	(cluster near2 tool) and semiconductor	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 16:17
-	34	(cluster near2 tool) and load near2 port	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 16:53
-	2778	414/935-941.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 16:54
-	402	(metrology or measuring or measure$4 or detect$3).ab,ti. and 414/935-941.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 17:04
-	31	((metrology or measuring or measure$4 or detect$3).ab,ti. and 414/935-941.ccls.) and seal$3 and environment	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 17:18

		13	metrology same semiconductor same load	USPAT; US-PGPUB; EPO; JPO; DERWENT	2003/01/29 17:19